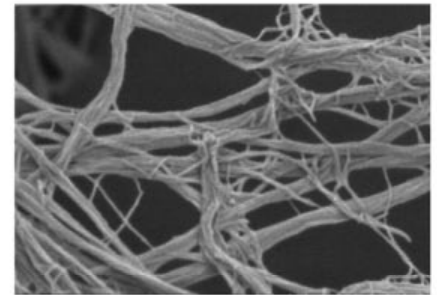
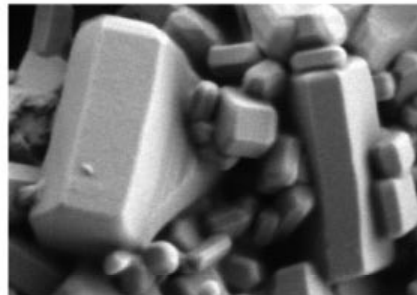


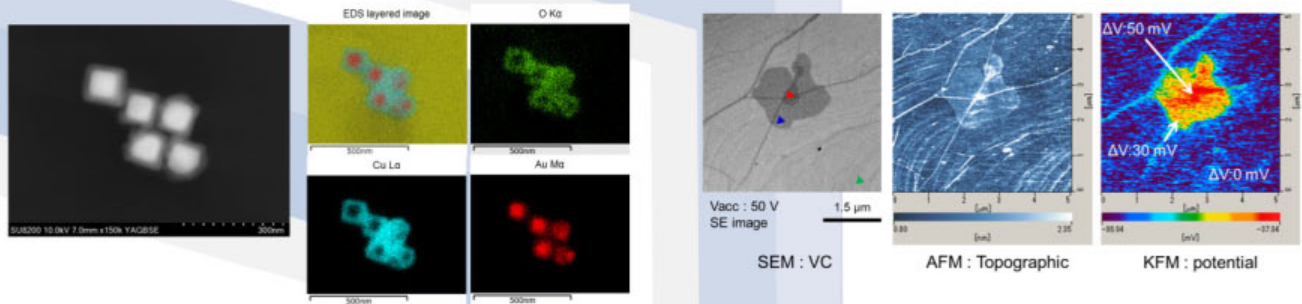
ELECTRON MICROSCOPY SEMINAR & WORKSHOP

17th JANUARY 2018

You are cordially invited to participate in our Electron Microscopy learning seminar and workshop to be held on 17th January 2018 in NSTDA, jointly organized by NSTDA Characterization and Testing Service Center (NCTC), Hitachi High-Technologies and Coax Group Co., Ltd. In this session, we aim to share some of the latest Electron Microscopy technology and techniques, relating to R&D, Failure Analysis and Quality Assurance in Thailand.



With the fast paced growth in technology and demand for high quality end products, R&D, Failure Analysis and Quality Assurance are playing important roles for every manufacturing company to keep up to industry standards. The Electron Microscope is no longer just a laboratory instrument, but an indispensable work horse equipment that forms a part of the manufacturing chain.



Techniques involving observation and analysis of new specimens in the Electron Microscopes are also constantly evolving to be applicable and ahead of the current needs. Ultra high resolution, true fine surface imaging, low-landing voltage and variable pressure techniques are some examples that we will share in this event.

Kindly refer to the next page for registration and event information.



Morning Seminar:

In the seminar session, we will kick-off with a presentation on the fundamentals of Electron Microscopes, explain the working concept for each type of Electron Microscopes, and using application examples to match each features of Electron Microscopes against various industrial application requirements.

Our presenter will discuss about various methods of sample preparations, which are critical for good EM imaging/analysis.

Just before lunch break, our presenter will share about the latest available technology and techniques, some know-hows to achieve the best results in imaging and analysis using the FE-SEM.



Afternoon Workshop:

In the afternoon, we will have an interactive live demonstration session in NCTC lab. Using industry related specimens, we will demonstrate and explain some of the techniques involved to get good data using Hitachi Ultra High Resolution FE-SEM and Variable Pressure FE-SEM. Additionally, we will also provide some sample preparation tips and surface preparation techniques using Ion Milling System; analyze the post milling data using the compact and easy Tabletop SEM system.



Registration:

For registration, please contact by email or phone to:

Hitachi High-Technologies Singapore Pte Ltd

Contact Person: Mr. Akira Tsuboyama 壺山晃

Email: akira.tsuboyama.ef@hitachi-hightech.com

Phone: +65-6597-7175

Time and Venue:

Date: 17 January 2018

Morning Seminar:

Time: 08:30 - 11:30

Venue: NSTDA, Central Building Lecture Room CO-113

Afternoon Workshop:

Time: 13:00 - 16:30

Venue: NSTDA, NCTC, INC2 Building Level 3.

แผนที่ห้องสัมมนาส่วนกลาง NSTDA Center map



Red boxed building is the seminar Venue.

Blue boxed area is car park for driving guest.

Thank you and looking forward to see you at the event.